



# Symetrix Corporation

## **Background**

- Symetrix has strong history as IP provider
  - *> 25 years of development*
  - *>200 U.S. and foreign patents.*
  - *> \$70M in research revenues, royalties and other income from development.*
- Symetrix has licensed various technologies to eleven separate companies.
- Several of these technologies are in high volume production, most notably FeRAM at Panasonic.

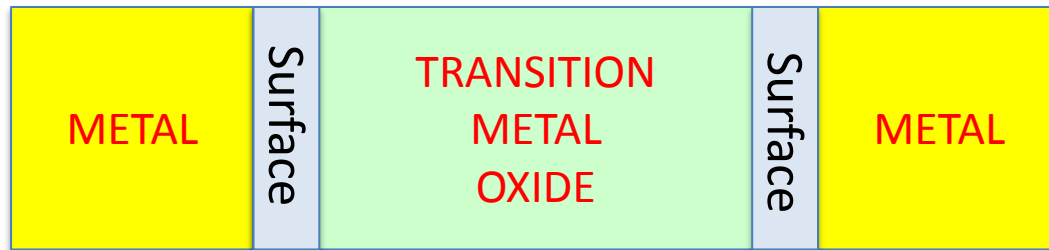
# Basic Idea of CeRAM

## Game Changer – No Filaments

- Control of material properties and proper device architecture are fundamental to this new paradigm. Evidence? No filament formation. (**No electroforming**)
- The CeRAM resistor is designed to exploit materials properties, surface properties, switching mechanism (endurance) and memory mechanism (retention).
- Optimizing CeRAM is a different science than building the perfect filament.

# Baseline

The device is like a diode (varistor) to start with:

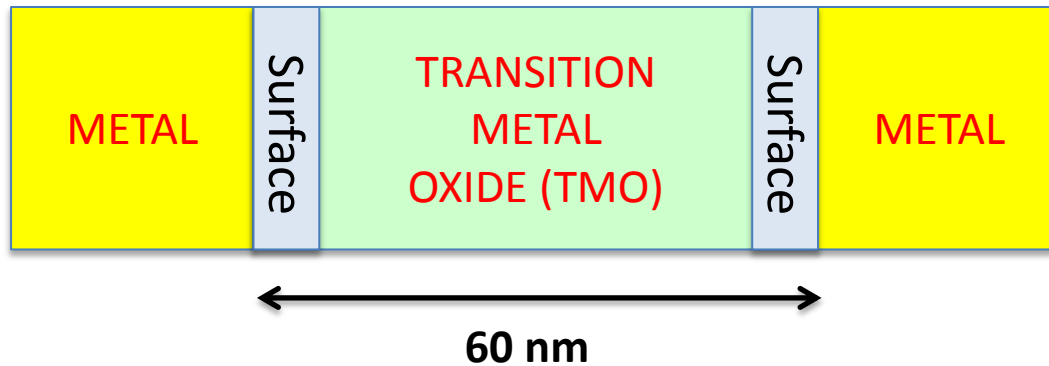


The surfaces are defect-rich with oxygen vacancies,  
transition metal excess, grain boundaries...

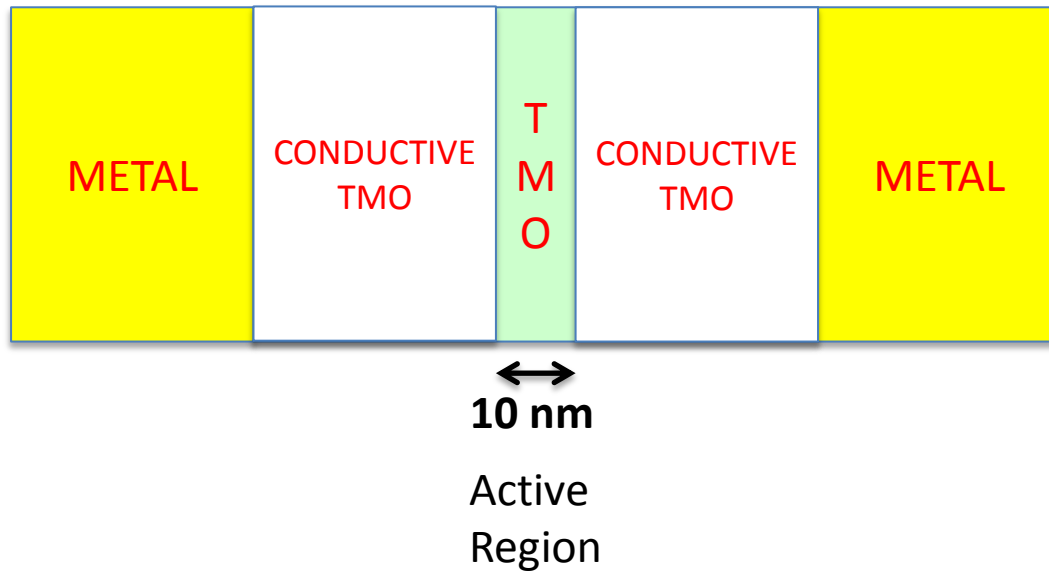
**And a schottky barrier !!**

# Baseline

ReRAM



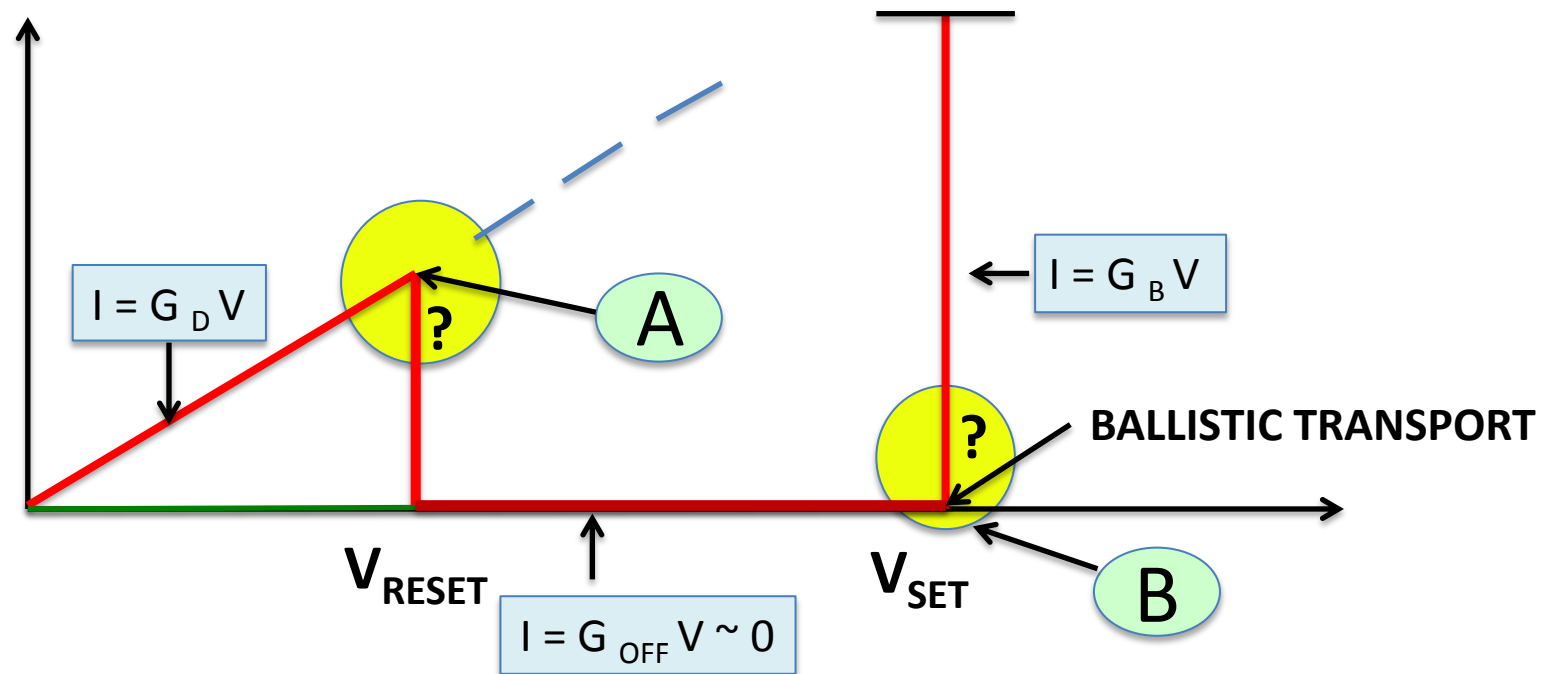
CeRAM



# Why the Layers?

- **Eliminate space charge** at the interface
- **Doping of TMO** to make it conductive as-deposited (valence stabilization)
- **Differential Doping** to create active region that is “switchable” and repeatable (“pure” phase transition)
- **Isolate and thin the active region** where the “electronic switch” property can be used exclusively----what electronic switching property? (Next slide)

# IV Characteristics - Device Physics

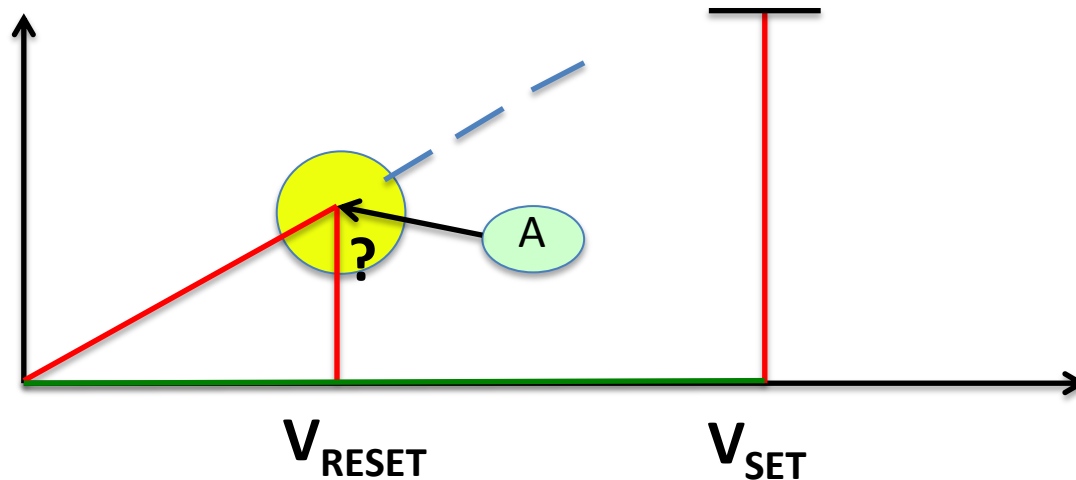


$G_D$  = **DIFFUSIVE TRANSPORT – DRUDE**

$G_B$  = **BALLISTIC TRANSPORT DUE TO  $e$ - $e$  CHARGE GAP  
CLOSING IN THE TRANSITION METAL ION 3d ORBITALS**

$G_{OFF}$  = **NO TRANSPORT IN INSULATING PHASE  
CONTROLLED BY  $e$ - $e$  REPULSION IN 3d ORBITALS**

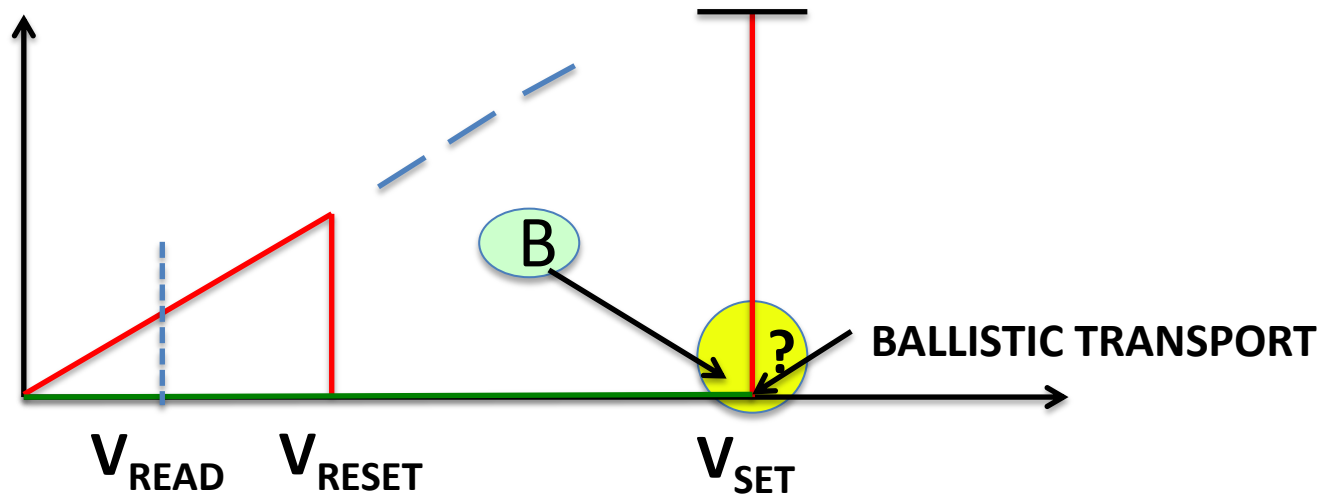
# Underlying Physical Mechanism



## A Is a quantum phase transition

- Mott, charge transfer (CT) but not Anderson
- Extended band gap is of no consequence here
- Only localized electron matters (in the atom)
- Extremely high speed – 80 femtoseconds

# Underlying Physical Mechanism

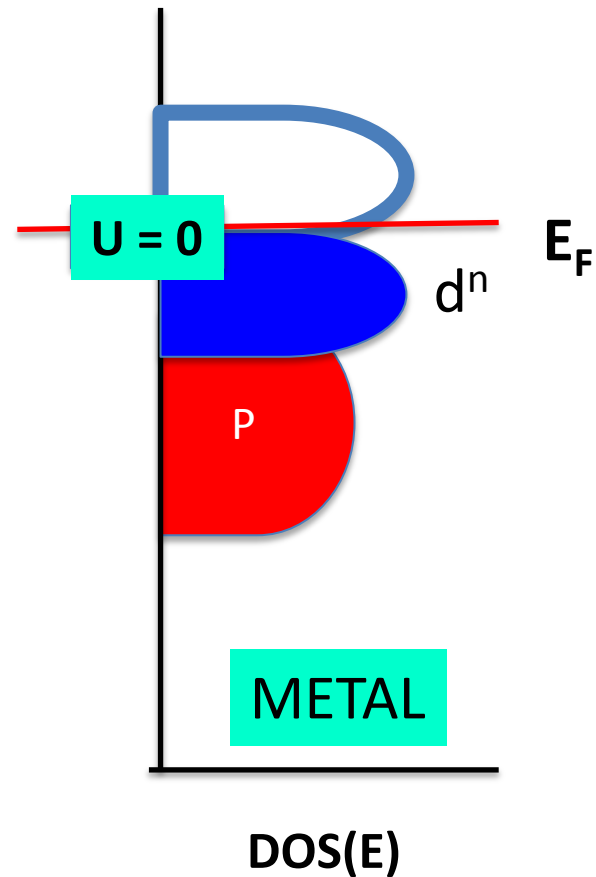
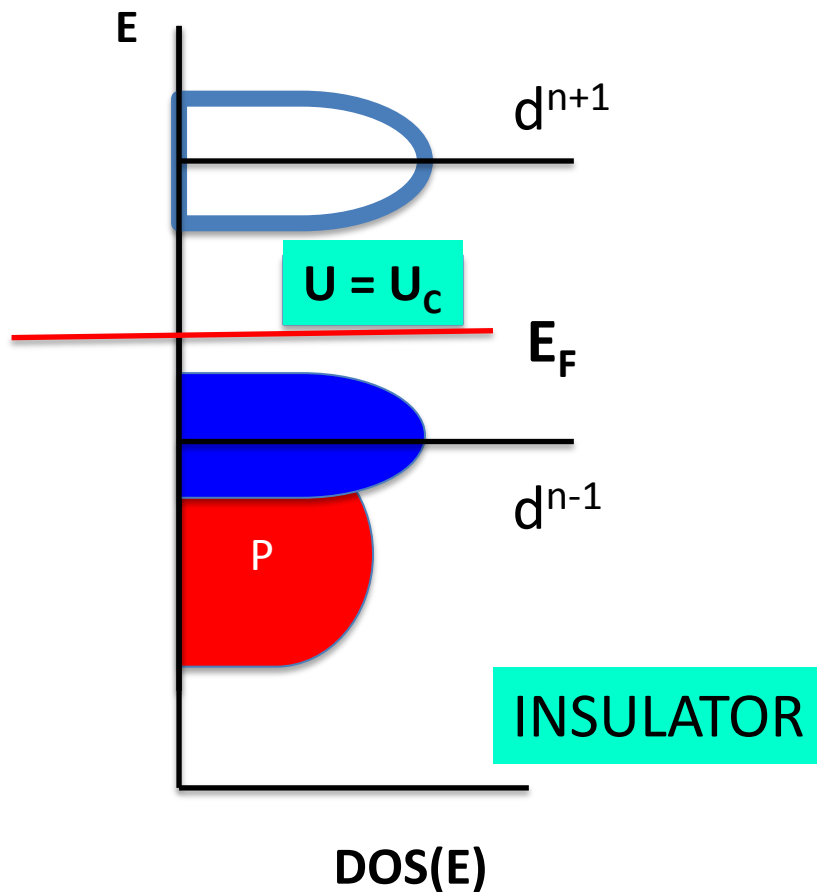


- B** Needs to be thermionic emission only  
to be sharp and **cohesive** so that it  
**matches the charge gap energy**  
**(no fluctuations)**



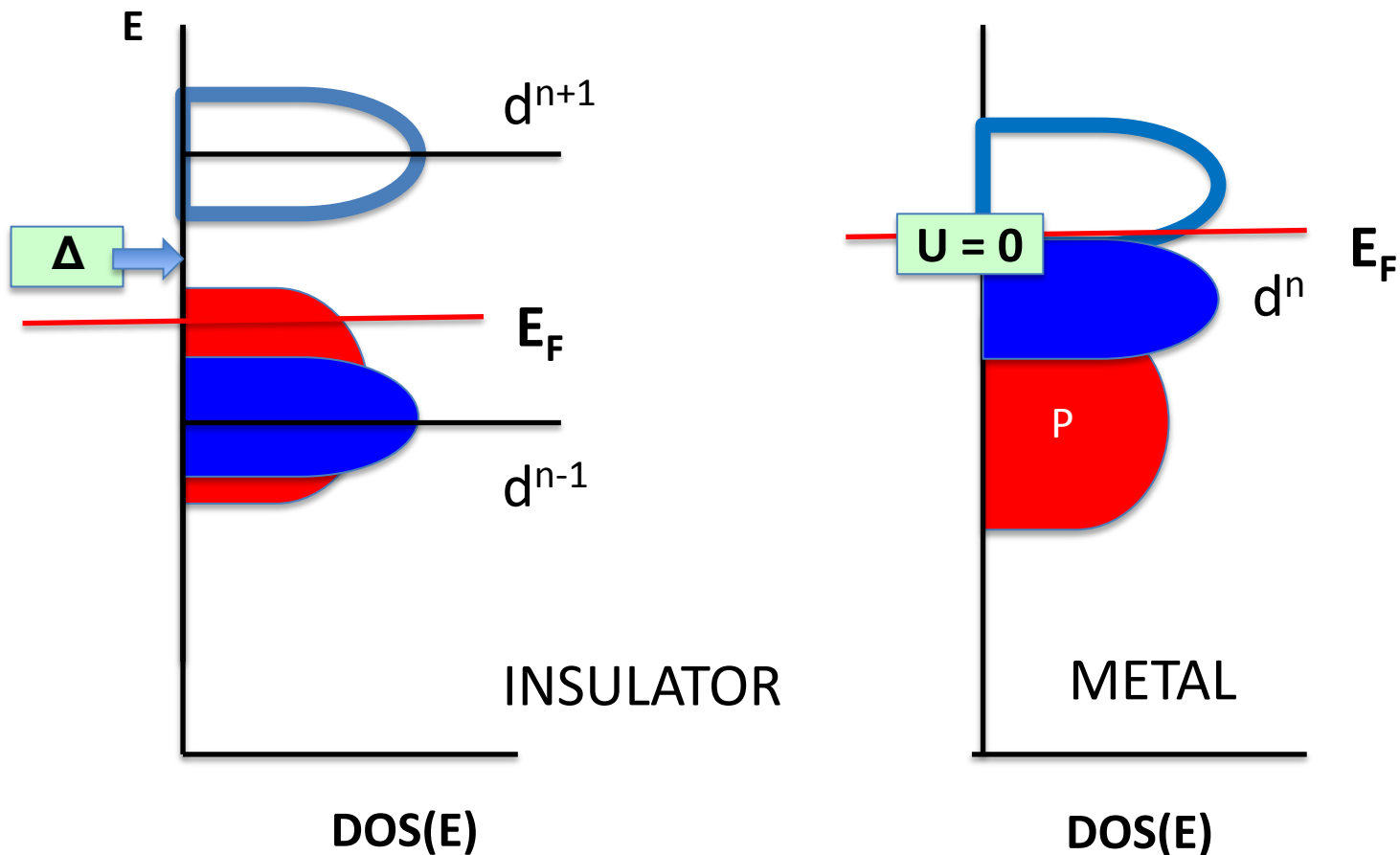
# Mott Insulators

## MOTT TYPE

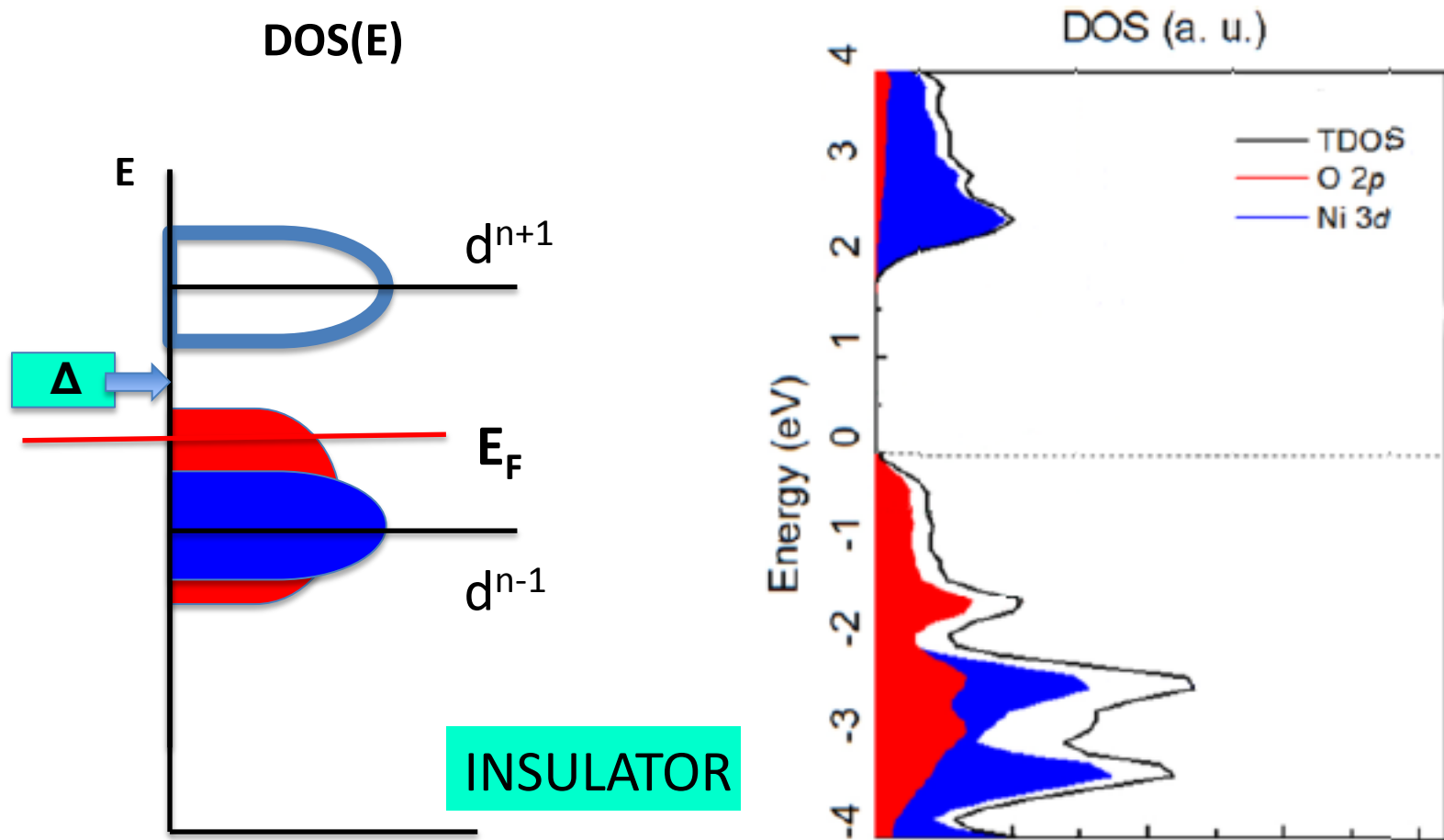


# Mott Insulators

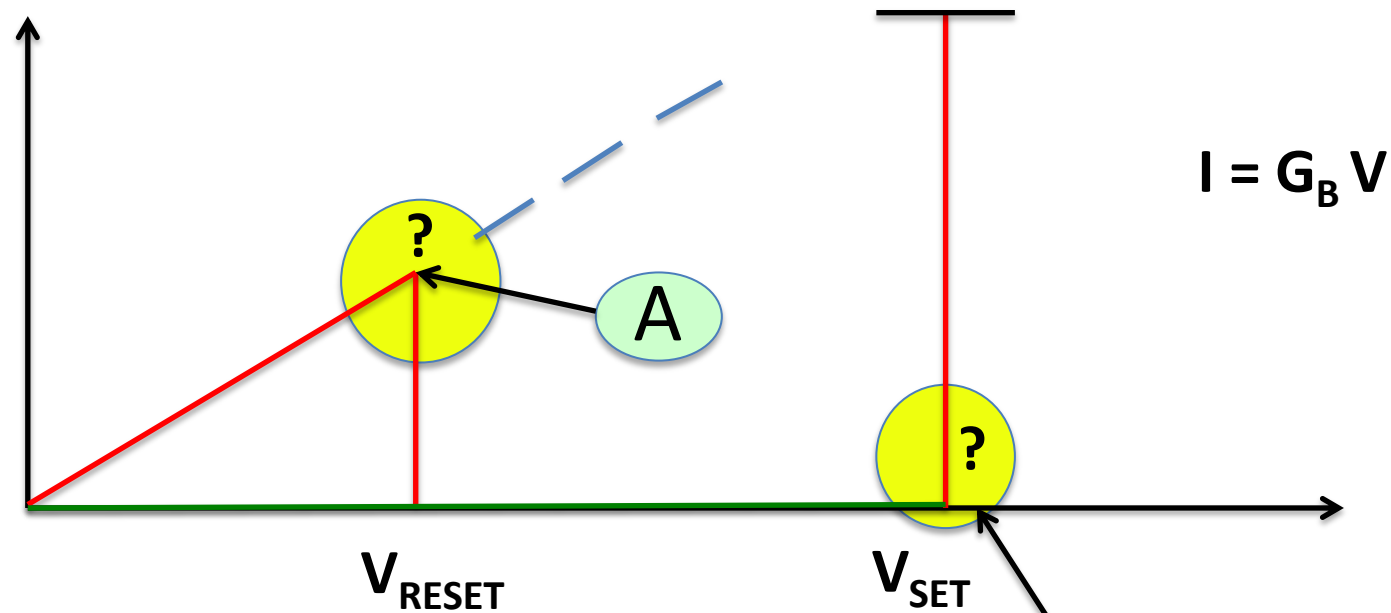
## CHARGE TRANSFER “MOTT INSULATOR”



# Charge Transfer M Mott Insulator



# IV Characteristics - Device Physics



A – FROM **METAL** TO INSULATOR PHASE TRANSITION

B – FROM INSULATOR TO **METAL** PHASE TRANSITION

# The Switch

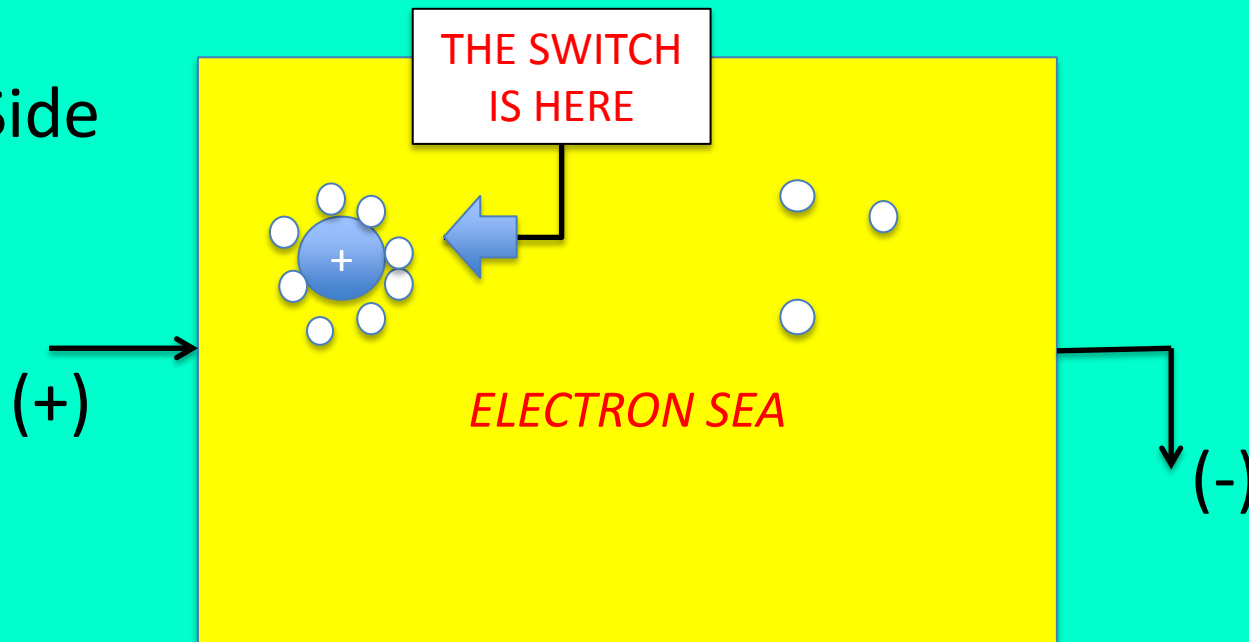
- The density of states modulates the screening length

$$\lambda_{\text{TF}} = \epsilon_0 / e^2 \text{DOS}(E_F)$$

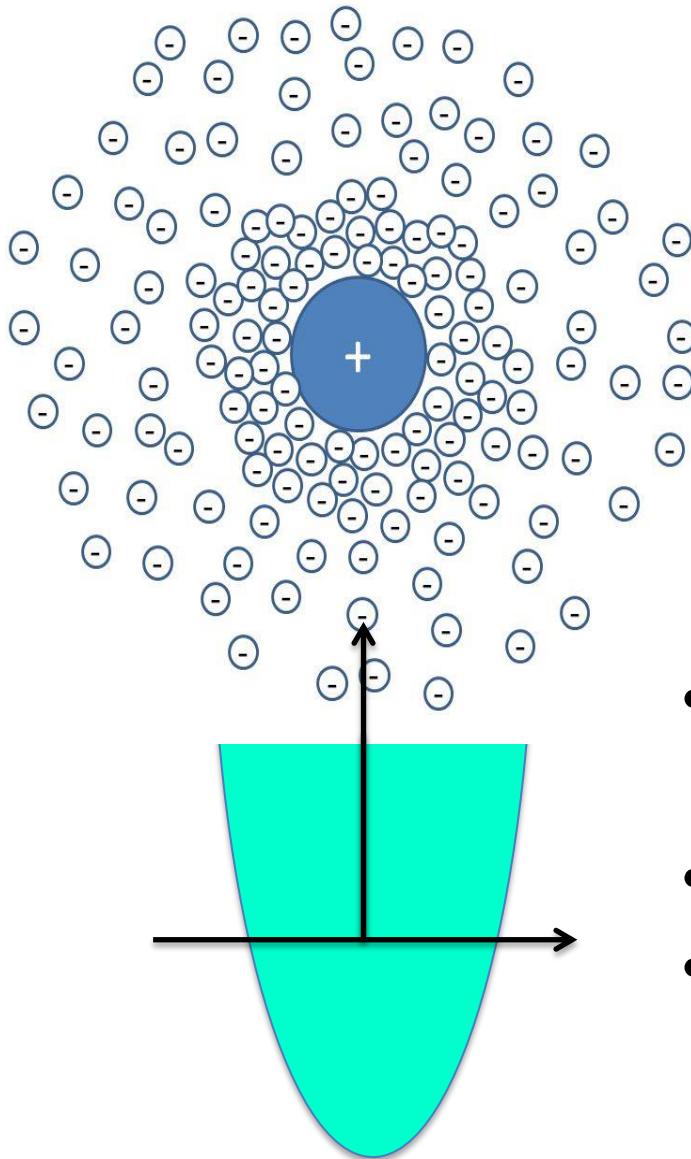
- The screening length modulates the current

$$J \approx 1 / \lambda_{\text{TF}}$$

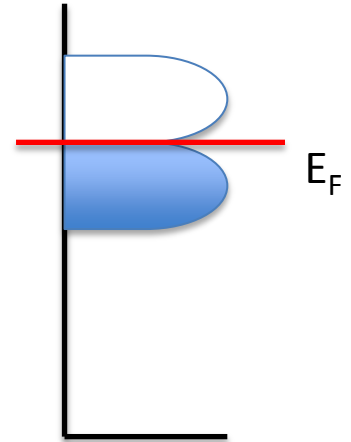
Metal Side



# Screening

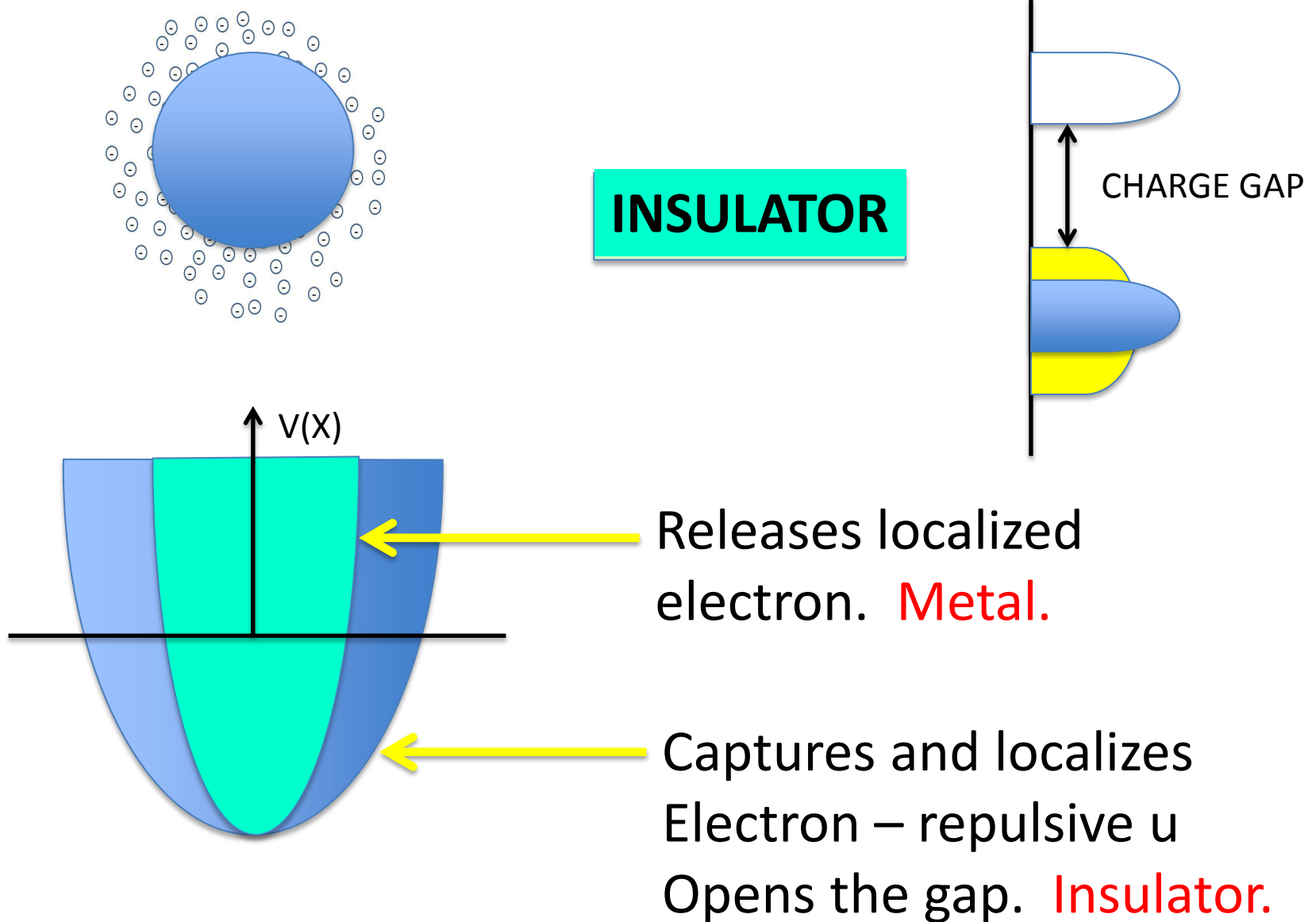


**METAL**



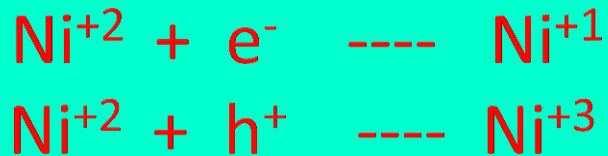
- Valence electrons screen the transition metal atom (ion)
- Narrows the potential well  $v(x)$
- Releases localized electron – closes the gap

# Screening

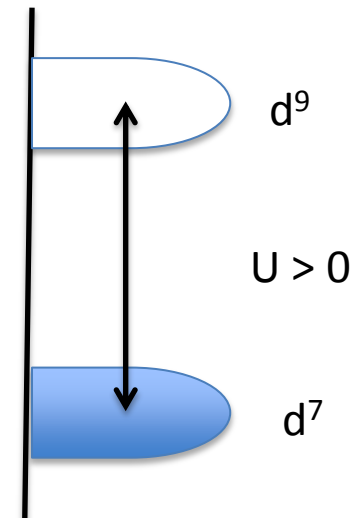


# Disproportionation

- A single atom can have oxidation and reduction reaction at the same time
- $GAP = I - A$        $I = \text{ionization energy}$      $A = e^- \text{ AFFINITY}$



*For Nickel (Oxide) ----  $d^8$  "splits"  
Into  $d^7$  and  $d^9$*





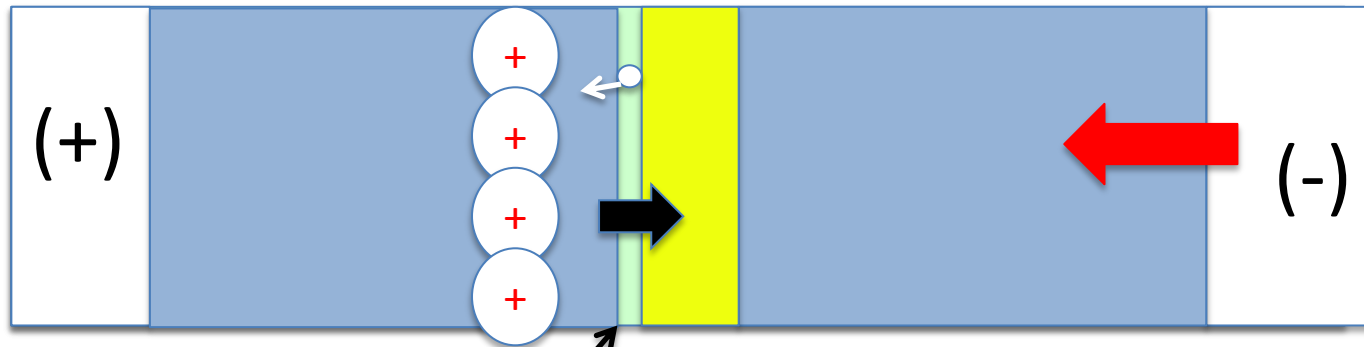
# Switching

SPEED OF PHASE TRANSITION IN **FEMTOSECONDS**

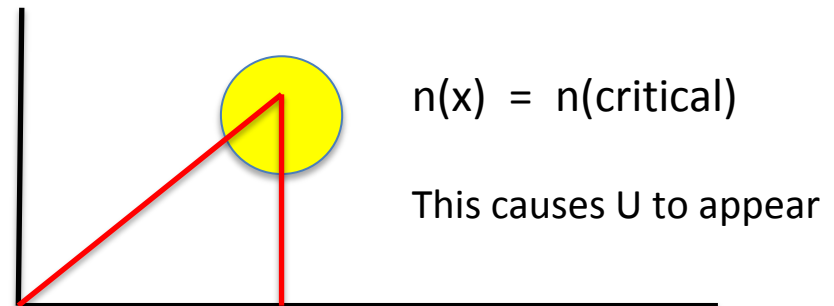


Active Region

ELECTRON DRIFT VELOCITY IN **NANOSECONDS**



**Electron deficient  
at reset**



# KEY POINTS

- The robustness of device switching requires control of the nickel ion oxidation number, specifically the suppression of  $\text{Ni}^{+4}$  and  $\text{Ni}^0$  species that inhibit the pure Mott transition:



- This is achieved with ligand doping, specifically  $\text{CO}^-$ .
- $\text{Co}^-$  doping stabilizes the CeRAM resistive element at  $\text{Ni}^{+2}$  and the NiO film is conductive as-deposited.
- There is no rupturing and reformation of filaments, there is no oxygen diffusion (Memristor), only a pure Mott (charge transfer) phase transition

# Technology Highlights

- Low temperature processing  $\sim 400^\circ\text{C}$
- Robust retention at 300-400  $^\circ\text{C}$  - proved
- Reading at 0.2 volts  $10^{12}$  times – proved
- Read memory widens with device scaling
- Variability reduced due to clean surfaces and isolated active region – proved
- Results demonstrated on  $0.8\mu\text{m}$  devices only. Smaller feature sizes have been recently enabled under a program with University of Texas at Dallas.

# CeRAM STATUS

- **THEORY:** Confirmed with empirical results → DONE
- **MATERIALS:** Doping any TMO with any extrinsic ligand  
→ PATENTED
- **PROCESS:** Create and isolate thin (5 nm) active region by simple spin-on or ALD → PATENT FILED
- **ARCHITECTURE:** Array only (no pass gate) → PATENTED
- **3-D (STACKING)** With only silicon friendly materials  
→ IN PROCESS
- **FPGA** Architecture → PATENT FILED

# Implications

*A NEW DEVICE AND THEORETICAL PARADIGM HAS BEEN DEVELOPED FOR RESISTIVE SWITCHING MEMORIES, ONE THAT:*

- Eliminates the oxygen diffusion effect (basis of memristor) to allow “pure” Mott-like transition.
- Reduces variability in key parameters ( $v_{\text{set}}$  &  $v_{\text{reset}}$ ) that has prevented ReRAM commercialization.
- Provides the robustness and repeatability required by future device scaling.
- Offers a path to 3d (stackable) memory architectures.
- May, in time, replace transistors as the fundamental switch in circuits.